



FORM PTO 1449 (modified)		ATTY DOCKET NO. 03560.003317		APPLICATION NO. 10/600,763	
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		APPLICANT NORIO OHKUMA			
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)		FILING DATE June 23, 2003		GROUP Unassigned	
September 23, 2003					
U.S. PATENT DOCUMENTS					
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	FILING DATE IF APPROPRIATE
<i>M</i>	6,113,222	09/2000	Ohkuma		
<i>M</i>	6,128,052	10/2000	Asaba et al.		
<i>M</i>	6,139,761	10/2000	Ohkuma		
<i>M</i>	6,143,190	11/2000	Yagi et al.		
<i>M</i>	6,305,080 B1	10/2001	Komuro et al.		
FOREIGN PATENT DOCUMENTS					
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	TRANSLATION YES/NO/ OR ABSTRACT
<i>M</i>	JP 10-181032	07/1998	Japan		Abstract*
<i>M</i>	JP 6-347830	12/1994	Japan		Abstract*
<i>M</i>	JP 9-11479	01/1997	Japan		Abstract*
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)					
<i>M</i>	E. Bassous, "Fabrication of Novel Three-Dimensional Microstructures by the Anisotropic Etching of (100) and (110) Silicon," IEEE Transactions on Electron Devices, October, 1978, Vol. ED-25, No. 10, pgs. 1178-1185.				
*Note: U.S. counterpart patents also submitted (see text of IDS).					
EXAMINER	<i>Robert Collett</i>		DATE CONSIDERED <i>12/3/04</i>		

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicants.
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